

TYPICAL PHOTOLITHOGRAPHY
RESIST APPLY/EXPOSE CELL

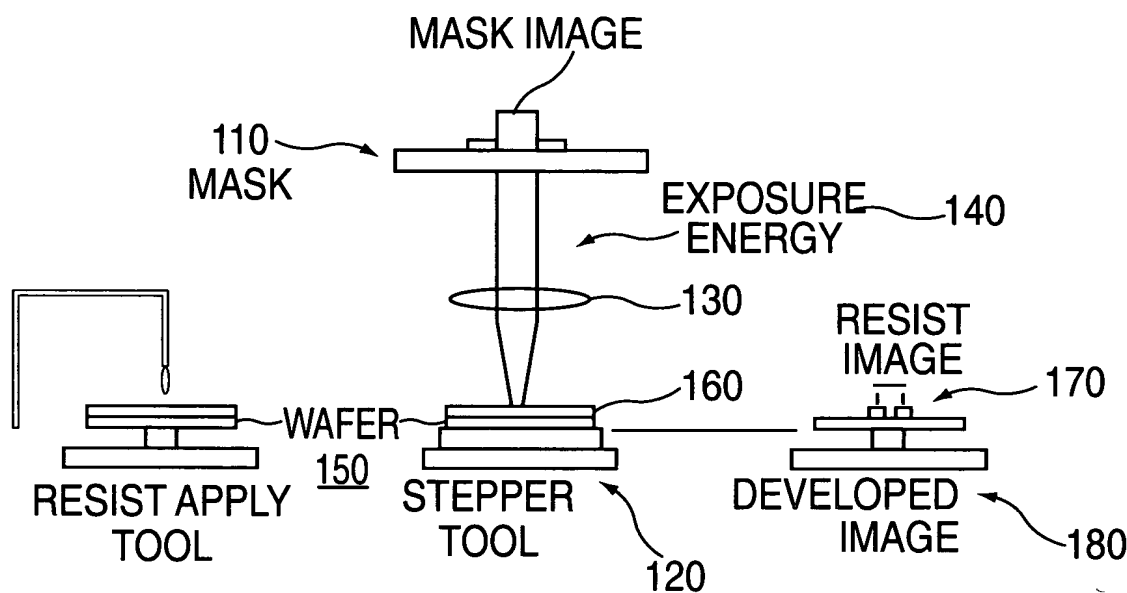


FIG. 1

TYPICAL RESIST
SUPPLY SYSTEM

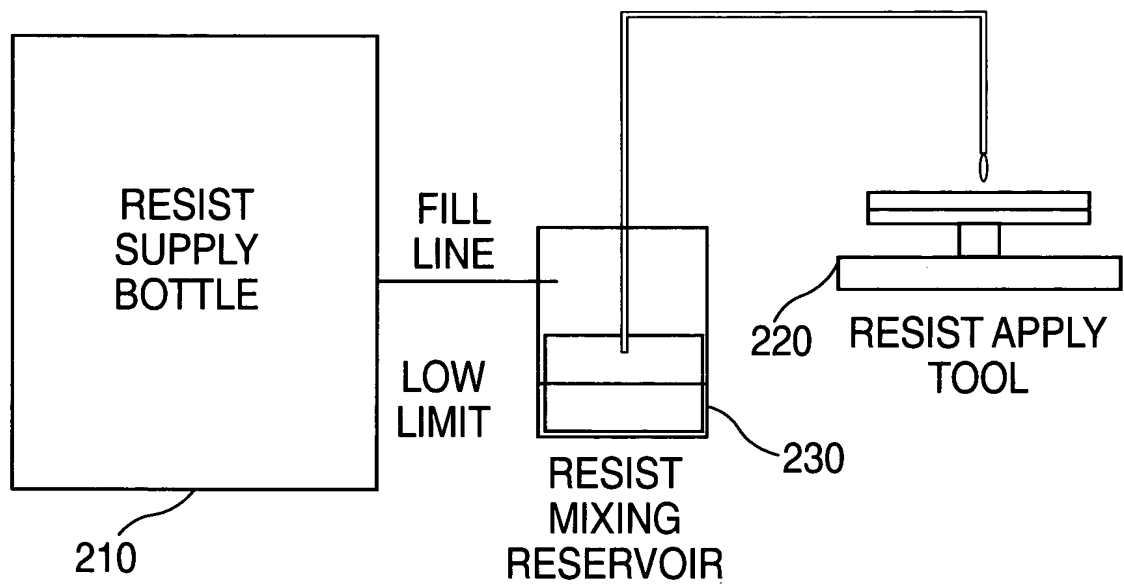


FIG. 2

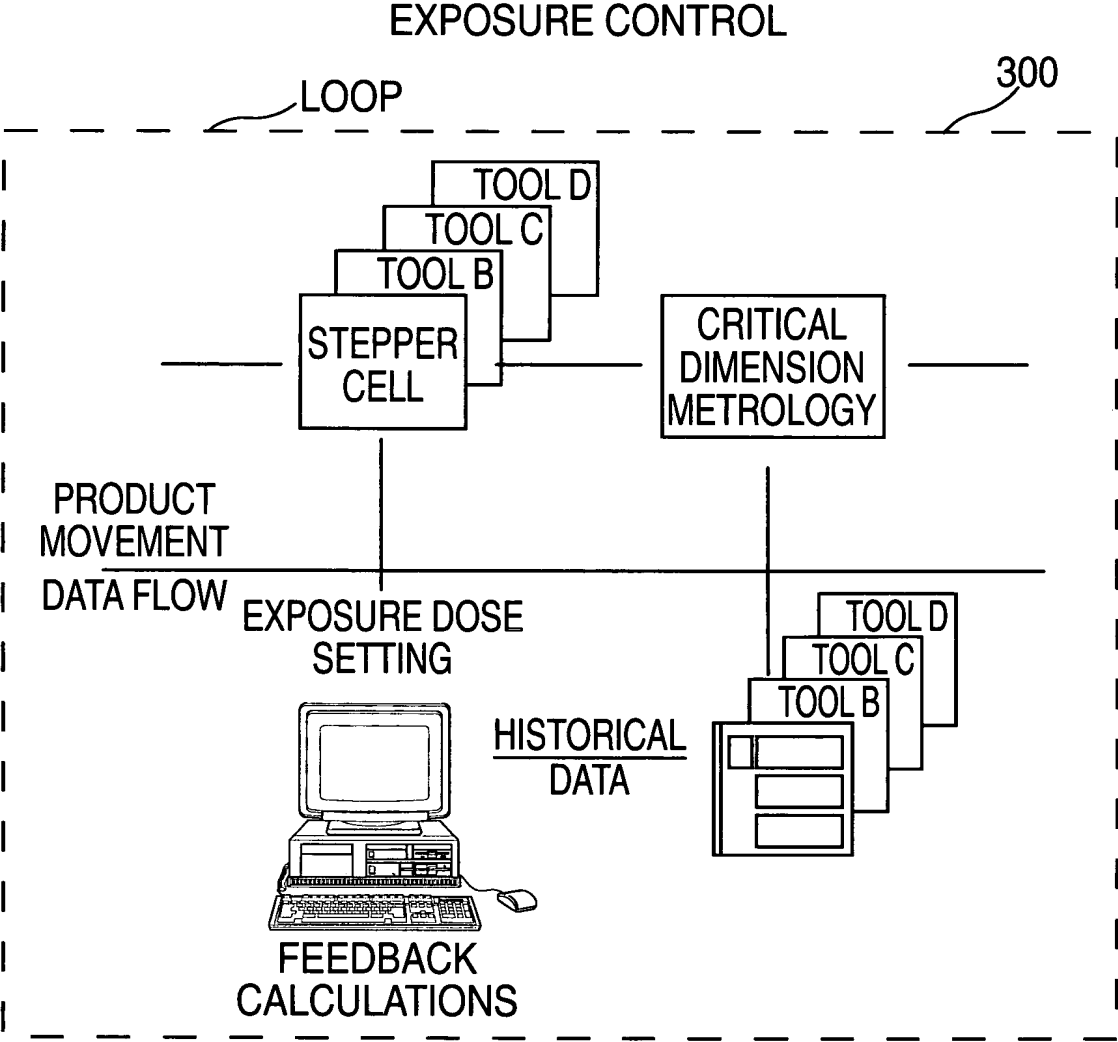


FIG. 3
(PRIOR ART)

EXPOSURE CONTROL LOOP WITH BATCH FACTOR ADJUSTMENTS

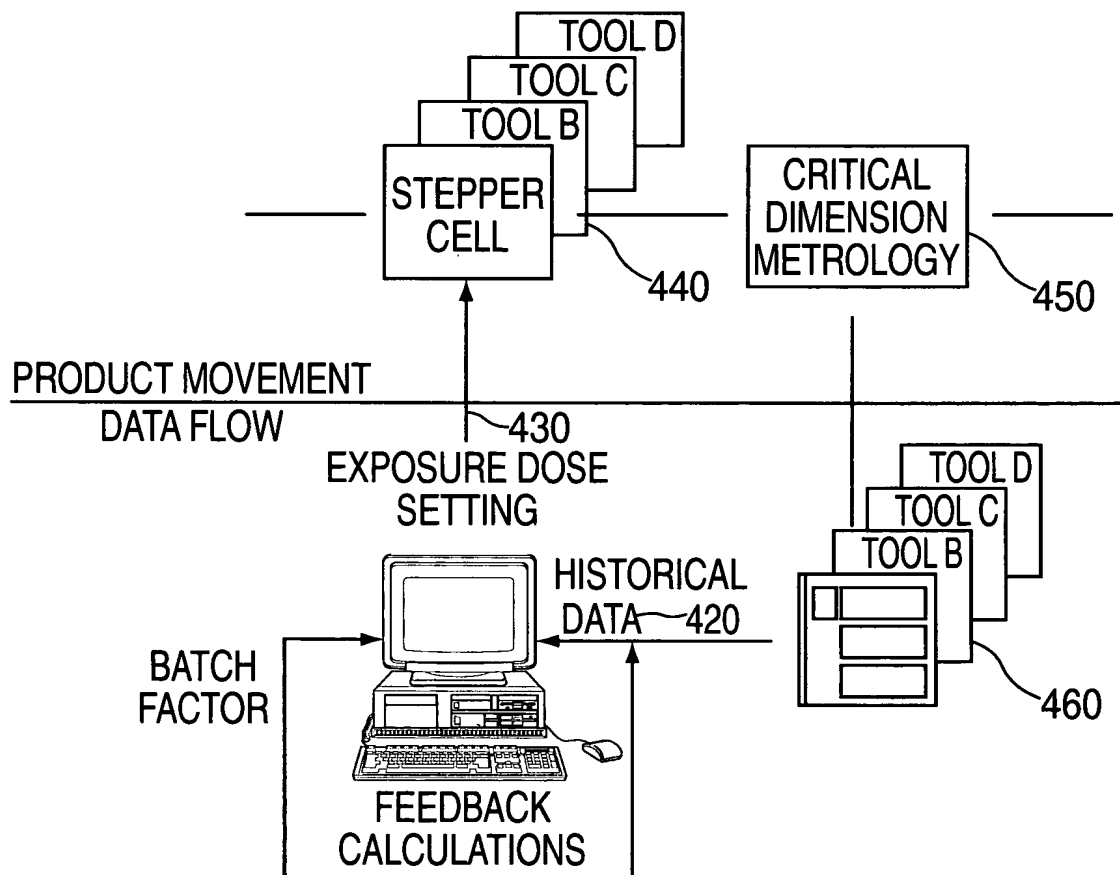


FIG. 4

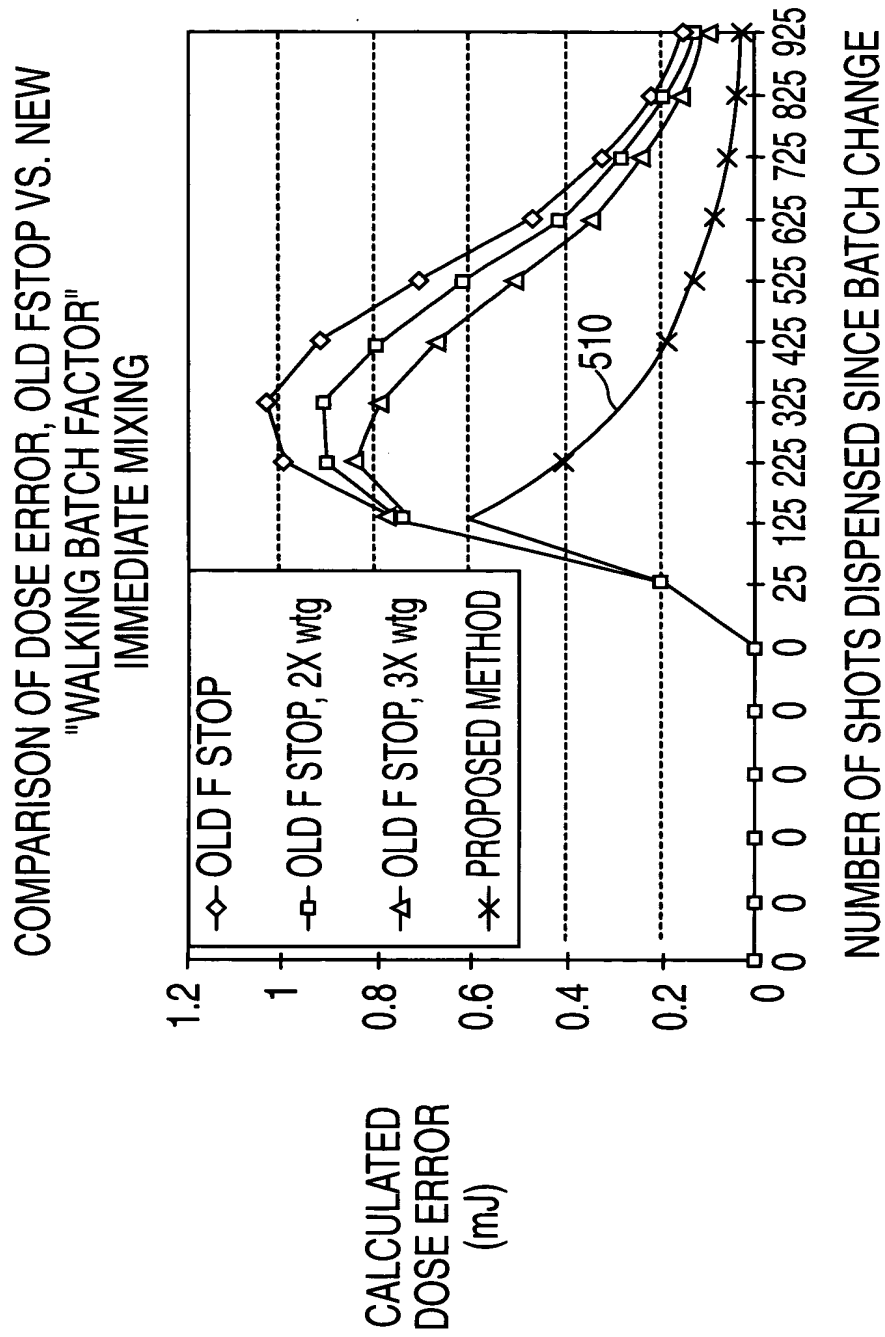


FIG. 5

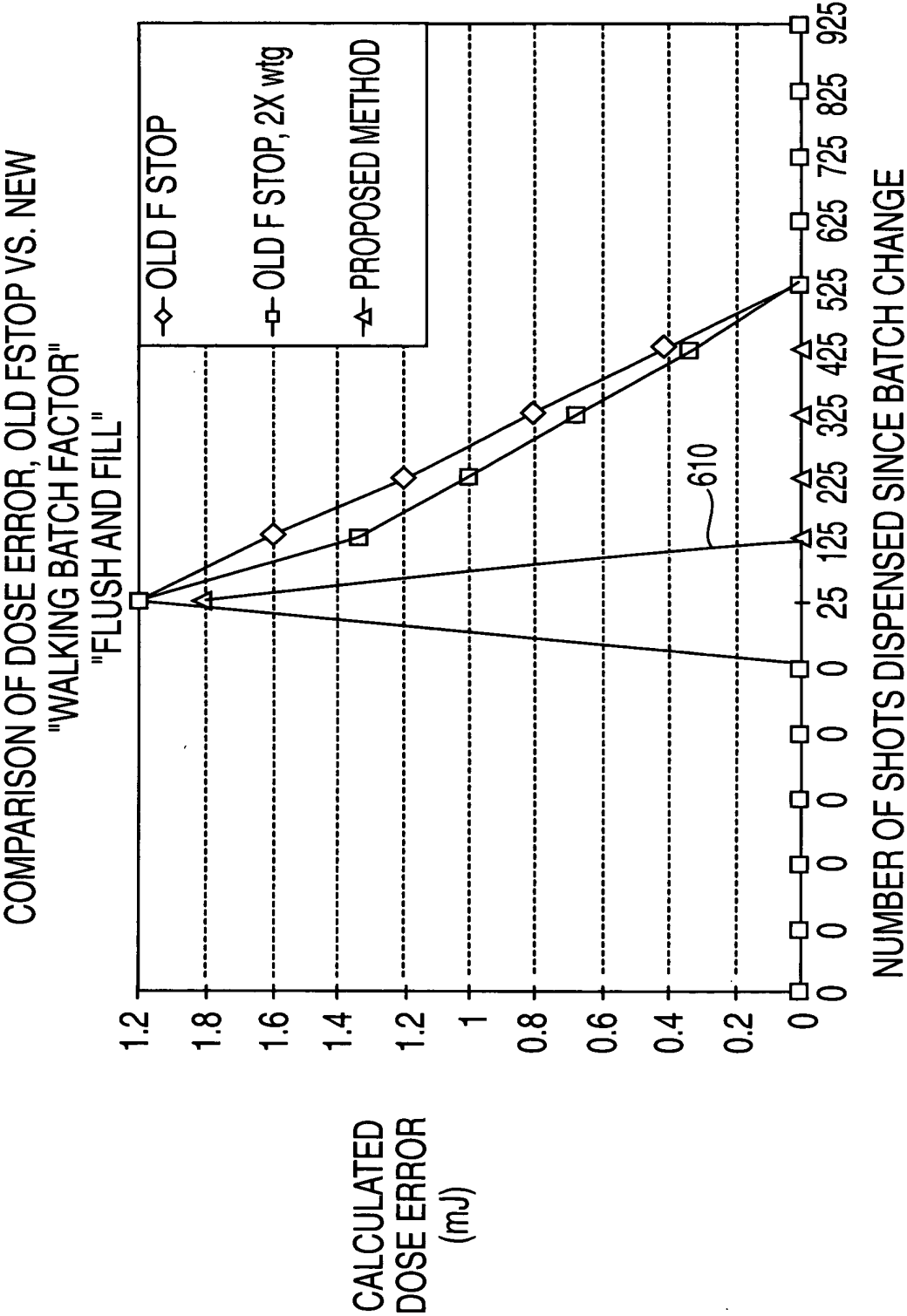


FIG. 6